

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Yi-Chiau Huang

Serial No.: 10/774,194

Confirmation No.: 6951

Filed: February 5, 2004

For: METHOD AND APPARATUS
FOR INFILM DEFECT
REDUCTION FOR
ELECTROCHEMICAL COPPER
DEPOSITION

Group Art Unit: 2823

Examiner: Quovaunda Jefferson

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING
37 CFR 1.8

I hereby certify that this correspondence is being deposited on November 4, 2005, with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

November 4, 2005
Date

Signature

RESPONSE TO OFFICE ACTION DATED AUGUST 23, 2005

In response to the Office Action dated August 23, 2005, having a shortened statutory period for response set to expire on November 23, 2005, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/008461/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Specification begin on page 2 of this paper. **Amendments to the Claims** are reflected in the listing of claims which begins on page 3 of this paper. **Remarks** begin on page 7 of this paper.